



Attorney Docket No. 04329.2409-00

PATENT

15W 262418
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Kei YOSHIKAWA et al

Application No.: 09/662,219

Filed: September 14, 2000

For: PATTERN CORRECTING
METHOD OF MASK FOR
MANUFACTURING A
SEMICONDUCTOR DEVICE AND
RECORDING MEDIUM HAVING
RECORDED ITS PATTERN
CORRECTING METHOD

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

PETITION FOR EXTENSION OF TIME

Applicants petition for a two-month extension of time to file a reply to the Office

Action dated April 6, 2007. The required fee of \$450.00 is enclosed.

Please grant any additional extensions of time required to enter the attached reply and charge any additional required fees to Deposit Account 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

By: _____

Reece Nienstadt
Reg. No. 52,072

Dated: September 6, 2007

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450.00 OP